# Monthly LabAdviser update: 28/9 2016

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| Updated Subject | Contributor | Link to the updated pages |
| **Sputter coater 03**  New sputter coater in the basement for use before SEM | **Pernille V. Larsen @danchip** | [Sputter\_coater#Sputter\_coater\_03](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Sputter_coater#Sputter_coater_03) |
| **ALD**  Standard recipe page updated:  TiO2 processes add and Al2O3 updated. | **Pernille V. Larsen**  **@danchip** | [ALD\_Picosun\_R200/Standard\_recipes\_on\_the\_ALD\_tool](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/Standard_recipes_on_the_ALD_tool) |
| **Equipment to be decommissioned**  This can no longer be found in LabAdviser. This is to be found on LabManager “Main” page. | **Thøger Eskildsen @danchip** | <http://labmanager.dtu.dk/function.php?module=Machine&view=currentinfo#decom> |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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|  | * APV and manual for Extraction box to prepare nano particles |
|  | * Manual for Plasma Asher1\_Model 300 Plasma Processor |
|  | * Manual for KS Aligner\_MA6 |
|  | * Manual for Developer: TMAH Manual |
|  | * Manual for Sputter system (LESKER) |
|  | * Manual for LPCVD Poly Silicon Furnace (6") (E2) |
|  | * Manual for Sputter Coater 03 |
|  | * Manual for Anneal Oxide furnace (C1) |
|  | * Manual for BCB Curing Oven |
|  | * Manual for III-V oxide furnace |

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